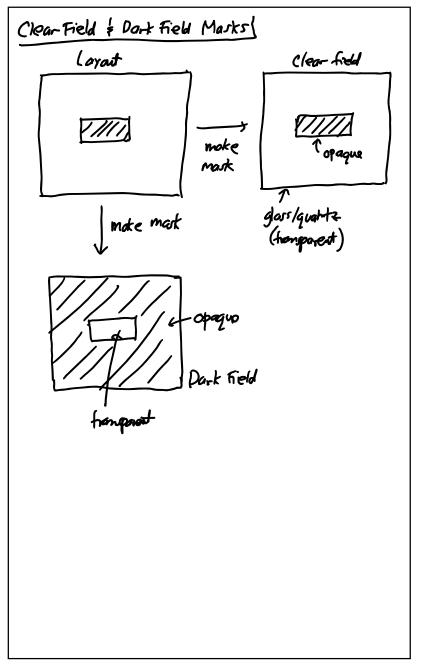
## Lecture 7: Surface Micromachining I

- · Announcements:
- · HW#2 due Tuesday, 2/25/20
- · Surface Micromachining Module 5 online
- -----
- · Today:
- Reading: Senturia Chpt. 3, Jaeger Chpt. 11,
   Handouts: "Surface Micromachining for Microelectromechanical Systems", "Etch Rates for Micromachining—Part II"
- · Lecture Topics:
  - \$ Polysilicon surface micromachining
  - **♦** Stiction
  - ♥ Residual stress
  - $\$  Topography issues
  - \$ Nickel metal surface micromachining
  - \$3D "pop-up" MEMS
  - \$Foundry MEMS: the "MUMPS" process
  - ♦ The Sandia SUMMIT process
- -----
- · Last Time:
- · Started into Module 5
- Now continue ...



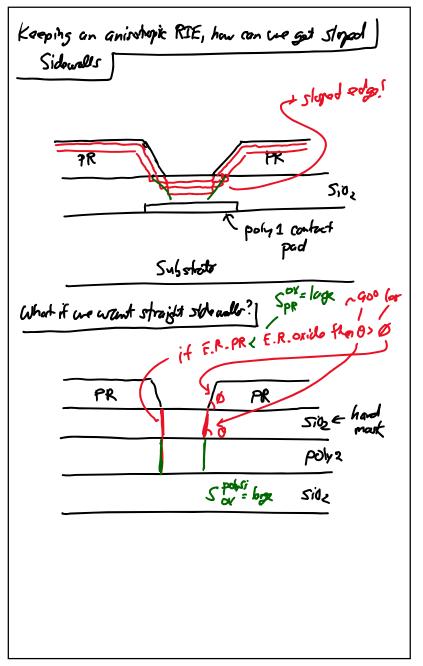
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## Lecture 7w: Surface Micromachining I

- · Straight or Sloped Sidewalls:
- Often want sloped sidewalls in order to reduce the sharpness of corners

  - \$ Sharp corners concentrate stresses
  - High stress can weaken structures creating a reliability concern
  - \$High stress can dissipate energy, lowering Q
- When you want straight sidewalls (e.g., for lateral electrostatic drive), use a hard mask
  - ♥ PR can't last for thick structures
  - ♦ A hard mask suppresses angle transfer

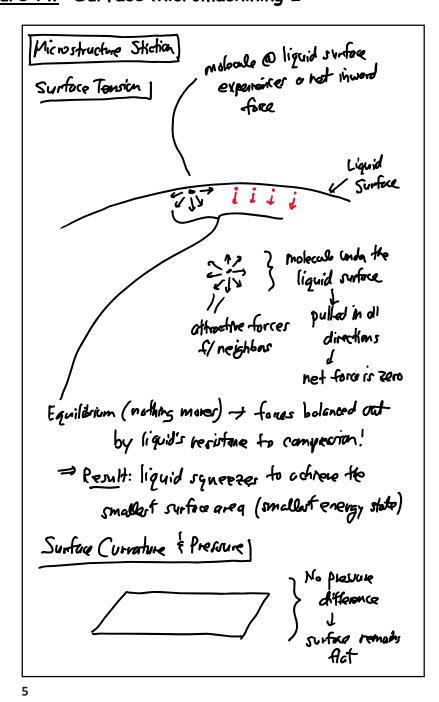
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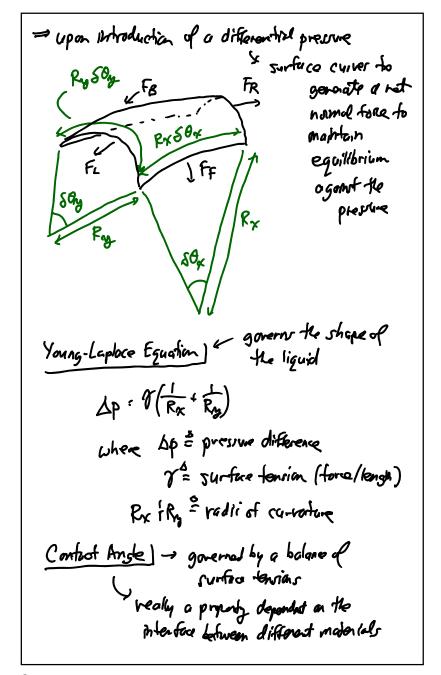


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## <u>EE C247B/ME C218</u>: Introduction to MEMS Lecture 7w: Surface Micromachining I





Lecture 7w: Surface Micromachining I

